## Amendments to the Claims:

The listing of claims will replace all prior versions, and listings, of claims in the application:

## <u>Listing of Claims</u>:

1-23. (Cancelled)

- 24. (Currently Amended) A vacuum cleaning chamber of Claim [[23]]

  25, wherein said workpiece holding arrangement is constructed to hold at least
  one disk shaped or plate-shaped workpiece, resides within said vacuum cleaning
  chamber and comprises at least one access slit slits are open to the interior of
  said vacuum cleaning chamber.
- 25. (Currently Amended) The chamber of Claim 24, wherein said holding arrangement defines for a holding plane for said disk-shaped or plate-shaped workpiece workpieces and said slit extends slits extend substantially parallel to said plane.
- 26. (Currently Amended) The chamber of Claim 25, wherein said slit extends slits extend laterally with respect to said holding plane.
  - 27.-28. (Canceled)

- 29. (Currently Amended) The chamber of Claim [[23]] <u>35</u>, wherein said plasma discharge section is a low-voltage discharge section.
- 30. (Previously Presented) The chamber of Claim 29, wherein said low-voltage discharge section comprises an electron-emitting hot cathode.
  - 31. (Canceled)
- 32. (Currently Amended) The chamber of Claim [[23]] <u>35</u>, wherein said tank arrangement feeds to said gas supply said gas comprising a working gas.
- 33. (Currently Amended) The chamber of Claim [[10]] 32, wherein said working gas [[is]] includes at least one noble gas.
  - 34. (Canceled)
- 35. (New) A vacuum treatment chamber for generating disk-shaped workpieces with directly bondable surfaces, said chamber being a stand-alone chamber in ambient, comprising a plasma discharge section, a gas supply operatively connected with a gas tank arrangement predominantly containing nitrogen, a workpiece holding arrangement comprising a magazine with slits, each slit being arranged for a workpiece to be simultaneously treated in said vacuum treatment chamber.